


10/531434  
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 / Ruth Montalvo Date: 04/15/05

Customer No. 026418

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Attorney's Docket No.: JG-SU-5213/500577.20067

U.S. Application No.:

International Application No.: PCT/JP2003/013320

International Filing Date: OCTOBER 17, 2003

17 OCTOBER 2003

Priority Date Claimed: OCTOBER 18, 2002

18 OCTOBER 2002

Title of Invention: METHOD FOR MEASURING POINT DEFECT DISTRIBUTION OF SILICON SINGLE CRYSTAL INGOT

Applicant(s) for (DO/EO/US): Kazunari KURITA and Jun FURUKAWA

Mail Stop PCT  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-450

**INFORMATION DISCLOSURE STATEMENT**

S I R:

Applicant herewith submits together with the simultaneously filed National Phase application of PCT/JP2003/013320, a copy of the International Search Report (PCT/ISA/210) dated January 20, 2004, citing some of the following references:

	Document Number	Date	Name and/or Country	English Translation
AA	6,045,610	04/04/2000	Park, et al.	
AL	2 324 652	10/28/1998	Great Britain	
AM	11-1393	06/01/1999	Japan	U.S. equivalent 6,045,610
AN	2002-47094	02/12/2002	Japan	Abstract only
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)				
AX	Abstract only of Publication No. 2002-102385 published 13APR01, Mitsubishi Materials Silicon, "Silicon wafer without aggregate of dot-like defect"			

Accompanying this Information Disclosure Statement and form PTO-1449 are first pages of the documents except AL (GB document complete) and English Abstracts. Documents AA, AM and AX are mentioned on page 3 of the substitute specification.

The USPTO waived the requirement under 37 C.F.R. §1.98(a)(2)(i) for submitting copies of US patents and US patent application publications in all U.S. applications filed after June 30, 2003.

10/531434

JC12 Rec'd PCT/PTO 15 APR 2005

This submission is not an admission that the information disclosed in the documents is material to the patentability of the invention disclosed and/or claimed in the above-identified application.

Respectfully submitted,



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Enclosures:

Search Reports (PCT/ISA/210);  
PTO-1449;  
First page of US document  
GB foreign document  
First pages of 2 JP documents  
2 English Abstracts

10/531434  
10-1449 Equivalent

**LIST OF PRIOR ART CITED BY APPLICANT**  
(Filed on April 15, 2005)

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Docket No. **JG-SU-5213/500577.20067**

Applicant(s): **Kazunari KURITA and Jun FURUKAWA**

Application No. (Int'l Appln No. PCT/JP2003/013320 17OCT03) Group:

Filed: Examiner:

**U.S. PATENT DOCUMENTS**

Exam. Init		Document Number	Date	Name	Class	Sub-Class	Filing Date Appropriate
	<b>AA</b>	<b>6,045,610</b>	<b>04/04/2000</b>	<b>Park, et al.</b>			
	<b>AB</b>						
	<b>AC</b>						
	<b>AD</b>						
	<b>AE</b>						
	<b>AF</b>						
	<b>AG</b>						
	<b>AH</b>						
	<b>AI</b>						
	<b>AJ</b>						
	<b>AK</b>						

**FOREIGN PATENT DOCUMENTS**

		Document Number	Date	Country	CLASS	Sub-Class	Translation YES NO
	<b>AL</b>	<b>2 324 652</b>	<b>10/28/1998</b>	<b>Great Britain</b>			
	<b>AM</b>	<b>11-1393</b>	<b>06/01/1999</b>	<b>Japan</b>			US 6,045,610
	<b>AN</b>	<b>2002-47094</b>	<b>02/12/2002</b>	<b>Japan</b>			Abstract only
	<b>AO</b>						
	<b>AP</b>						
	<b>AQ</b>						
	<b>AR</b>						
	<b>AS</b>						
	<b>AT</b>						

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	<b>AX</b>	<b>Abstract only of Publication No. 2002-102385 published 13APR01, Mitsubishi Materials Silicon, "Silicon wafer without aggregate of dot-like defect"</b>
	<b>AY</b>	
	<b>AZ</b>	

Examiner:	Date:
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.